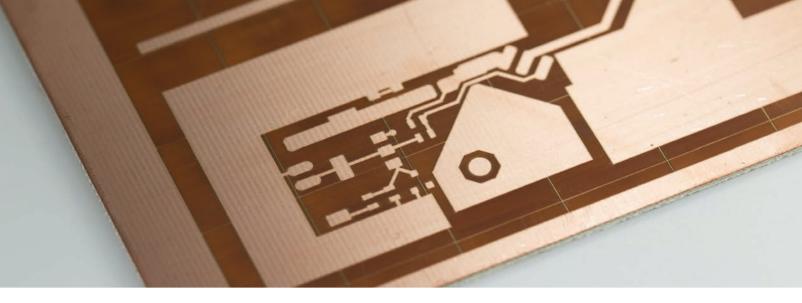




EXPEGO SPLIT AXIS MACHINE

VERSATILE LASER SYSTEM
FOR MICRO MATERIAL PROCESSING

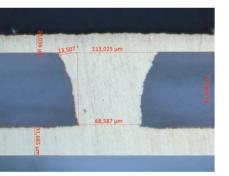


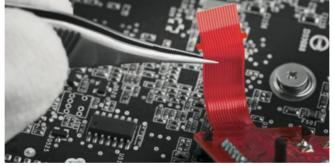
FEATURES

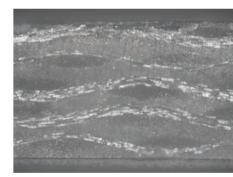
- Ultra fast laser technology
- Single or dual process head setup
- In-situ scanner calibration
- Double table option
- Automatic laser to camera offset calibration
- Automated vision system for precision alignment and scaling, offset, trapezoidal and rotation compensation
- Stand alone or production line integrated system
- XL-Scan (simultaneous axis and scanner movement)

OPTIONS

- Import of CAD files (e.g. DXF, DWG, Gerber)
- SQL data base for process and event tracking
- MES interface (SECS,GEM,PV2, OPC,UA)
- Integrated process metrology
- Semi-automatic handling (R&D)
- Fully-automatic handling (production)







APPLICATIONS

Micro Via Drilling, Routing, Depaneling, Micro Structuring, Selective Ablation, Cavity Formation

ACCURACY

 $< +/-10 \mu m abs.$

< +/-2 µm repeatability

SUBSTRATES

Dimension up to 29.5" x 25" (750 mm x 635 mm)

Rigid-, flex-PCBs, ceramic, glass and advanced materials

AVAILABLE LASER SOURCES

Wavelength: 9.4, 10.6 μm (CO₂), 1064, 1030, 532, 515, 355 nm

Pulse: us, ns, ps, fs

DIMENSIONS

1750 x 2200 x 2600 mm



PRODUCT

PRESENTATION